

**Finland-Espoo: Miscellaneous general and special-purpose machinery**  
**OJ S 193/2023 06/10/2023**  
**Contract award notice**  
**Supplies**

**Legal Basis:**

Directive 2014/24/EU

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**Section I: Contracting authority**

**I.1. Name and addresses**

Official name: VTT Technical Research Centre of Finland Ltd

National registration number: 2647375-4

Postal address: P.O. Box 1000, VTT

Town: Espoo

NUTS code: FI1 Manner-Suomi

Postal code: 02044

Country: Finland

E-mail: [kilpailutus@vtt.fi](mailto:kilpailutus@vtt.fi)

Telephone: +358 20722111

**Internet address(es):**

Main address: <https://www.vttresearch.com/en>

**I.4. Type of the contracting authority**

Body governed by public law

**I.5. Main activity**

Other activity: Research and development

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**Section II: Object**

**II.1. Scope of the procurement**

**II.1.1. Title**

Plasma ALD

**II.1.2. Main CPV code**

42900000 Miscellaneous general and special-purpose machinery

**II.1.3. Type of contract**

Supplies

**II.1.4. Short description**

The object of the tender is a 2-chamber Plasma Enhanced Atomic Layer Deposition Cluster with Automatic Wafer Handling (later also "Equipment" and/or "Tool") for coating of 200mm wafer substrates, or substrates that can be placed on such carrier wafers, with different metals, nitrides and oxides with process separation between metals/nitrides and oxides, and wafer handling from chamber-to-chamber and chamber-to-cassette without vacuum breaking. The object of the tender process is described in more detail in the invitation to tender documents.

#### **II.1.6. Information about lots**

This contract is divided into lots: no

#### **II.1.7. Total value of the procurement**

Value excluding VAT: 1 586 196,00 EUR

### **II.2. Description**

#### **II.2.3. Place of performance**

NUTS code: FI1B Helsinki-Uusimaa

Main site or place of performance: Espoo

#### **II.2.4. Description of the procurement**

The object of the tender is a 2-chamber Plasma Enhanced Atomic Layer Deposition Cluster with Automatic Wafer Handling (later also "Equipment" and/or "Tool") for coating of 200mm wafer substrates, or substrates that can be placed on such carrier wafers, with different metals, nitrides and oxides with process separation between metals/nitrides and oxides, and wafer handling from chamber-to-chamber and chamber-to-cassette without vacuum breaking. The object of the tender process is described in more detail in the invitation to tender documents.

#### **II.2.5. Award criteria**

Price

#### **II.2.11. Information about options**

Options: yes

Description of options:

The contracting entity may procure the following or some of the following optional features from the contract supplier (see Annex 1):

- Optional feature 1: gas line and in-situ production of ozone (O3) for chamber dedicated to oxides
- Optional feature 2 : integrated ellipsometry hardware for one chamber

Offering optional features is not mandatory. Optional features are not taken into account in the price comparison of tenders.

#### **II.2.13. Information about European Union funds**

The procurement is related to a project and/or programme financed by European Union funds: yes

Identification of the project: The procurement is related to EU\_PREVAIL-project (Partnership for Realization and Validation of AI hardware Leadership) financed by EU funds.

#### **II.2.14. Additional information**

### **Section IV: Procedure**

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#### **IV.1. Description**

##### **IV.1.1. Type of procedure**

Open procedure

##### **IV.1.3. Information about a framework agreement or a dynamic purchasing system**

##### **IV.1.8. Information about the Government Procurement Agreement (GPA)**

The procurement is covered by the Government Procurement Agreement: yes

## **IV.2. Administrative information**

### **IV.2.1. Previous publication concerning this procedure**

Notice number in the OJ S: [2023/S 096-301971](#)

### **IV.2.8. Information about termination of dynamic purchasing system**

### **IV.2.9. Information about termination of call for competition in the form of a prior information notice**

## **Section V: Award of contract**

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### **Title:**

Plasma ALD

A contract/lot is awarded: yes

### **V.2. Award of contract**

#### **V.2.1. Date of conclusion of the contract**

06/09/2023

#### **V.2.2. Information about tenders**

Number of tenders received: 1

Number of tenders received from SMEs: 0

Number of tenders received from tenderers from other EU Member States: 1

Number of tenders received by electronic means: 1

The contract has been awarded to a group of economic operators: no

#### **V.2.3. Name and address of the contractor**

Official name: Veeco GmbH

National registration number: DE258288047

Town: Aschheim/Dornach Munich

NUTS code: DE Deutschland

Country: Germany

The contractor is an SME: no

#### **V.2.4. Information on value of the contract/lot**

Total value of the contract/lot: 1 586 196,00 EUR

#### **V.2.5. Information about subcontracting**

## **Section VI: Complementary information**

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### **VI.3. Additional information**

### **VI.4. Procedures for review**

#### **VI.4.1. Review body**

Official name: Markkinaoikeus

Postal address: Sörnäistenkatu 1

Town: Helsinki

Postal code: 00580

Country: Finland

E-mail: [markkinaoikeus@oikeus.fi](mailto:markkinaoikeus@oikeus.fi)

Telephone: +358 295643300

Internet address: <http://www.oikeus.fi/markkinaoikeus>

**VI.5. Date of dispatch of this notice**

03/10/2023